

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: Not yet assigned  
Applicants: Christian DUSSARRAT, et al.  
Filed Internationally: April 8, 2004  
US National: Herewith  
Title: METHODS FOR PRODUCING SILICON NITRIDE FILMS BY VAPOR-PHASE GROWTH  
TC/A.U: Unknown  
Examiner: Unknown  
Docket No.: Serie 6070  
Customer No.: 000040582

INFORMATION DISCLOSURE STATEMENT

Commissioner of Patents  
P.O. Box 1450  
Washington, D.C. 20231

Dear Sir:

In accordance with the duty of disclosure as set forth in 37 C.F.R. § 1.56, Applicants hereby submit the following information in conformance with 37 C.F.R. §§ 1.97 and 1.98. Pursuant to 37 C.F.R. § 1.98, a copy of each of the non-US patent documents cited on the enclosed PTO Form 1449 is enclosed.

No fee is due at this time in accordance with 37 C.F.R. § 1.97. However, the Commissioner is hereby authorized to charge any appropriate fees under 37 C.F.R. §§ 1.16, 1.17 and 1.21 that may be required by this paper, and to credit any overpayment, to Deposit Account No. 01-1375. This paper is submitted in duplicate.

Respectfully submitted,

  
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Linda K. Russell, Registration No. 34,918

Date: October 17, 2005

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**EXAMINER:** Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.